LIST OF DOCUMENTS CITED BY APPLICANT

(Use several sheets if necessary)

ATTY DOCKET NO. 18940/36899

SERIAL NO.

APPLICANT

M. Toshiyuki, Y. Masami, H. Yoshihiro

November 2, 2000

-2858

2829

ENT B

## U.S. PATENT DOCUMENTS

EXAMINER		DOCUMENT NUMBER	DATE		_		FR. STO CLATE F APPROPRIATE	
INITIAL				NAME	CLASS	SUBCLASS		
TH	AA	3,753,373	8/21/1973	Brown				
D	AB	4,473,796	9/25/1984	Nankivil				
- AL	AC	4,498,044	2/5/1985	Horn				
D	AD	5,416,470	5/16/1995	Tanaka et al.	·			
AL.	ΑĘ	5,701,101	12/23/1997	Weinhardt et al.	٠			
M	AF	5,808,516	9/15/1998	Barber				
Si_	AG	5,886,529	3/23/1999	Wakamatsu				
D	АН	5,986,456	11/16/1999	Yamashita				
De	Al	6,054,867	4/25/2000	Wakamatsu	~		]	
	AJ							
	AK							

## FOREIGN PATENT DOCUMENTS

			·				TRANSLATION	
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Yes	No
P-	AL	3413849 A1	8/22/1985	Germany				
A.	АМ	61-14578	1/22/1986	Japan				
<u>a</u>	AN	06180336	6/28/1994	Japan (Abstract)	نب			1
<u>A</u>	AO	4135991 C1	12/17/1992	Germany			$oxed{L}$	
D	AP	9-280806	10/31/1997	Japan				

OTHER PRIOR ART (Including Author, Title, Date Pertinent Pages, Etc.)

		OTHER PRIOR ART (Including Author, Title, Date Periment Pages, Etc.)
F	AQ	An On-Chip, Attofarad Interconnect Charge-Based Capacitance Measurement (CBCM Technique), J.C. Chen, B.W. McGaughy, D. Sylvester, C. Hu, Department of EECS, University of California Berkeley, 1996
D2_	AR	On-Chip Measurement of Interconnect Capacitances in a CMOS Process, A. Khalkhal and P. Nouet, Laboratoire d'Informatique, de Robotique et de Microelectronique de Montpellier (LIRMM), Proc. IEEE 1995 Int. Conference on Microelectroic Test Structures, Vol. 8, March, 1995
<u>J</u>	AS	Efficient extraction of metal parasitic capacitances, G.J. Gaston and I.G. Daniels, GEC Plessey Semiconductors Ltd., Proc. IEEE 1995 Int. Conference on Microelectronic Test Structures, Vol. 8, March, 1995

2	•	_		4	
SIA AT		Op-emp circuit measure Engineer's notebook, El	s diode-junction capacit ectronics, July 10, 1975	tance, by D. Monticelli and T.	Frederiksen,
EXAMINER:			STE CONSTREED:		
*EXAMINER: In	nitial if ref	erence considered, whether or	not citation is in conforma	nce with MPEP 609; Draw line thro	ugh citation if not in
conformance as	nd not co	nsidered. Include copy of this	form with next communica	tion to applicant.	

O AN 1 8 2001

44422v1